

Notice of References Cited

Application/Control No.

09/890,864

Applicant(s)/Patent Under

Reexamination
HAUSSLER ET AL.

Examiner

Brian L. Mutschler

Art Unit

1753

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A		US-4,207,119	06-1980	Tyan, Yuan-Sheng	138/258
B		US-5,220,181	06-1993	Kanai et al	257/40
C		US-			
D		US-			
E		US-			
F		US-			
G		US-			
H		US-			
I		US-			
J		US-			
K		US-			
L		US-			
M		US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N						
O						
P						
Q						
R						
S						
T						

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Page(s)
U		Schaffer et al., The Science and Design of Engineering Materials (1995) pp. 40-41.
V		Tjhen et al., "Properties of Piezoelectric Thin Films for Micromechanical Devices and Systems," MEMS 1991 Proceedings, IEEE, (1991) pp. 114-119.
W		Kirk-Othmer Encyclopedia of Chemical Technology, Physical properties of zinc oxide and pure copper.
X		

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.02(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.